

1 Docket No. VRO-20.01

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WAFER HANDLER METHOD AND SYSTEM

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ABSTRACT

6 **[0065]** Systems and methods for handling wafers include retrieving a first wafer from a wafer  
7 cassette using a first arm, transferring the first wafer from the first transfer arm to a second arm,  
8 delivering the first wafer for processing to a process chamber using the second arm, removing the  
9 first wafer from the process chamber using the first arm, and returning the first wafer to the  
10 cassette using the first arm. The systems and methods can include retrieving a first wafer from a  
11 wafer cassette using a first arm, delivering the first wafer for processing to a process chamber  
12 using the first arm, removing a processed wafer from the process chamber using a second arm,  
13 returning the processed wafer to the cassette using the second arm, and iteratively retrieving,  
14 delivering, removing and returning wafers from the cassette while alternating arms between  
15 iterations.